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PATENT  
IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

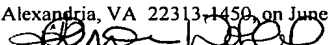
Application No. : 10/625,243  
Applicant: : PERRY, A.  
Filed: : July 22, 2003  
Title: : METHOD AND SYSTEM FOR ELECTRONIC  
SPATIAL FILTERING OF SPECTRAL  
REFLECTOMETER OPTICAL SIGNALS

TC/A.U. : 1765  
Examiner : Vinh, L.

Atty. Docket No. : LAM2P426  
Date : June 7, 2005

Mail Stop Amendment  
Commissioner for Patents  
P.O. Box 1450  
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CERTIFICATE OF MAILING

I hereby certify that this correspondence is being deposited with the United States Postal Service as First Class Mail in an envelope addressed to: Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450, on June 7, 2005.  
Signed:   
Rick von Wohld

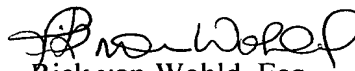
RESPONSE TO RESTRICTION REQUIREMENT

Sir:

In response to the Restriction Requirement dated May 10, 2005, Applicant hereby elects, without traverse, claims identified as Group II (claims 8-9, 19-23, drawn to a system for etching a wafer capable of determining endpoint of a plasma etching/a plasma processing system/apparatus, classified in class 156, subclass 345/25), to prosecute on the merits in the above-identified patent application.

Should the Examiner have any questions concerning this matter, the undersigned can be reached at the telephone number below.

Respectfully submitted,  
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Attorney Docket No. LAM2P426